

# Pyroelectric Properties of Sol-Gel Derived Lithium Tantalite Thin Films

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## Abstract

Lithium tantalite ( $\text{LiTaO}_3$ ) thin films ( $\sim 0.5\mu\text{m}$ ) have been successfully deposited on  $\text{Pt}(111)/\text{SiO}_2/\text{Si}(100)$  substrates by means of sol-gel spin-coating technology. Figures of merit for infrared detector were studied for the  $\text{LiTaO}_3$  thin films. There exists high figures of merit  $F_v$  of  $2.1 \times 10^{-10} \text{ C}\cdot\text{cm}/\text{J}$  and  $F_m$  of  $2.4 \times 10^{-8} \text{ C}\cdot\text{cm}/\text{J}$  because of the relative low dielectric constant ( $\epsilon_r$ ) of 35 and high pyroelectric coefficient ( $\gamma$ ) of  $4.0 \times 10^{-8} \text{ C}/\text{cm}^2\cdot\text{K}$  of the films. The pyroelectric infrared detector fabricated by the  $\text{LiTaO}_3$  thin film exhibits a voltage responsivity  $R_v$  of 4584 V/W at 20 Hz and a high specific detectivity  $D^*$  of  $4.23 \times 10^7 \text{ cm}\cdot\text{Hz}^{1/2}/\text{W}$  at 100 Hz.

*Key words:*  $\text{LiTaO}_3$ ; sol-gel; thin film; voltage responsivity; specific detectivity

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In recent years, pyroelectric detectors have been widely used for infrared (IR) detection applications owing to the advantages of wavelength-independent sensitivity and room temperature operation. There are commonly used materials for pyroelectric applications including triglycene sulphate (TGS), lithium tantalite ( $\text{LiTaO}_3$ ),  $\text{Ba}_{1-x}\text{Sr}_x\text{TiO}_3$  (BST), PZT and  $\text{PbTiO}_3$  [1]. In which,  $\text{LiTaO}_3$  is a suitable material with high figures of merit for pyroelectric detector application. In this study, it is focused on the optical response of the  $\text{LiTaO}_3$  thin film IR detectors fabricated by a sol-gel method with the 1, 3-propanediol solvent. The 1, 3-propanediol can be capable of intermolecular association reactions, and is of low toxicity and air stable. The study of the dynamic response of diol-based sol-gel derived  $\text{LiTaO}_3$  thin films presented in this work is original and has never been published elsewhere.

The sol-gel process is used to prepare the precursor solutions of  $\text{LiTaO}_3$  with general chemical formula.

Lithium 2,4-pentanedionate,  $\text{LiC}_5\text{H}_7\text{O}_2$  and tantalum isopropoxide,  $\text{Ta}[\text{OCH}(\text{CH}_3)_2]_5$  were used as precursors and 1,3-propanediol,  $\text{HO}(\text{CH}_3)_2\text{OH}$  was used as solvent. The details of the diol-based sol-gel technique and the synthesis process of  $\text{LiTaO}_3$  film have been reported previously [2]. The films were deposited on  $\text{Pt}(111)/\text{SiO}_2/\text{Si}(100)$  substrates by repeated spin-coating at a spin rate of 3000 rpm for 30 s. After each coating step, the films were given a pyrolysis heat treatment at 400 °C for 30 min to remove residual organics. Finally, films with five-layers were fabricated, then heated in air at 700 °C for 1 h.

To measure the optical responses of the  $\text{LiTaO}_3$  thin film detectors, a light source from a blackbody furnace with a temperature of 1000 K was focused, using a concave lens, and mechanically chopped at frequencies from 5 Hz to 1 kHz. The pyroelectric voltage and current signals were measured using a lock-in amplifier (Model EG&G-7260) and monitored by a digitizing oscilloscope (Model HP-54502A), while the detector was exposed to the incident chopped-IR radiation. These measurements were performed at room temperature, in a shielded room.

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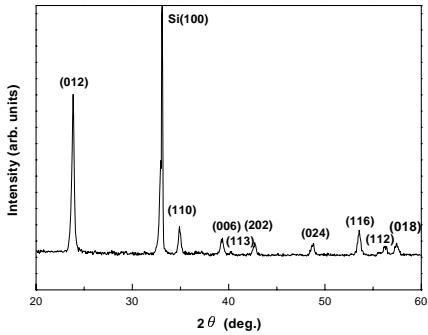


Fig. 1. XRD pattern of LiTaO<sub>3</sub> film heated at 700 °C for 1 h.

Figure 1 shows the XRD pattern of LiTaO<sub>3</sub> thin film heated at 700 °C for 1 h. It is obvious that the polycrystalline lithium tantalite can be obtained. The ratio of the standard XRD intensities of LiTaO<sub>3</sub> powder,  $I(hkl)$ , from the JCPDS file is:  $I(012) : I(110) : I(006) : I(202) : I(116) : I(018) = 100 : 25 : 4 : 16 : 20 : 6$ . In this study, we can find that the diffraction intensities of these planes are quite similar to those of the standard powder sample.

The pyroelectric coefficient  $\gamma$  of the LiTaO<sub>3</sub> thin film heated at 700 °C for 1 h can be measured by ramping the temperature of the material at a rate of 3 °C/min. The maximum value of  $\gamma$ , the pyroelectric coefficient, was calculated to be about  $4.0 \times 10^{-8}$  C/cm<sup>2</sup>·K at 62 °C. The average figures of merit,  $F_v = \gamma/C_V \cdot \epsilon_r$  for the voltage responsivity,  $R_v$ , and  $F_m = \gamma/C_V (\epsilon_r \cdot \tan \delta)^{1/2}$  for the specific detectivity,  $D^*$ , of the LiTaO<sub>3</sub> thin films were estimated to be  $2.1 \times 10^{-10}$  C·cm/J and  $2.4 \times 10^{-8}$  C·cm/J, respectively [2]. These values are much larger than those of PZT [ $F_v = 0.5 \times 10^{-10}$  C·cm/J and  $F_m = 1.6 \times 10^{-8}$  C·cm/J] [3].

The optical response of LiTaO<sub>3</sub> thin film IR detector is expressed in terms of voltage responsivity ( $R_v$ ) given by [4]:

$$R_v = \frac{\eta \gamma A R \omega}{\sqrt{1 + \omega^2 \tau_t^2} \sqrt{1 + \omega^2 \tau_e^2}}, \quad (1)$$

where  $\omega$  is the angular modulation frequency,  $\tau_t$  the thermal time constant ( $= H/G$ , where H and G are the thermal capacity and the thermal conductance, respectively.), and  $\tau_e$  ( $= RC$ ) is the electrical time constant. The specific detectivity ( $D^* = R_v (\Delta f A)^{1/2} V_n$ ) gives the area-normalized signal to noise ratio in the frequency bandwidth  $\Delta f$  for the detector. Figure 2 shows the modulation frequency dependence of  $R_v$ ,  $D^*$  and voltage noise  $V_n$  for LiTaO<sub>3</sub> thin film IR detector.

The  $R_v$  value decreases at high frequencies because  $R_v$  is inversely proportional to the frequency at a modulation frequency  $> \tau_t^{-1}$ . The present results are consistent with the above phenomenon described by equation (1). The detector has a maximum voltage repon-

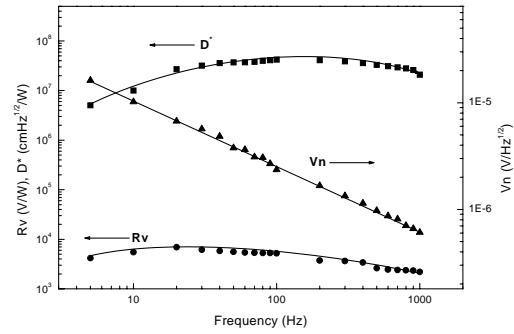


Fig. 2. The modulation frequency dependence of  $R_v$ ,  $D^*$  and voltage noise  $V_n$  for LiTaO<sub>3</sub> thin film IR detector.

sivity  $R_v$  of 4584 V/W at 20 Hz. Figure 2 also shows that  $V_n$  varied nearly proportionately to  $f^{-1/2}$ , possibly because Johnson noise dominated in pyroelectric detectors [5].  $D^*$  was proportional to  $f^{-1/2}$  for  $f > 100$  Hz, because  $R_v$  varied proportionately to  $f^{-1}$  and  $V_n$  varied with  $f^{-1/2}$ . In contrast,  $D^*$  decreased as  $f$  decreased for  $f < 50$  Hz. This phenomenon probably occurred because  $R_v$  was almost saturated, and  $V_n$  increased nearly proportionately to  $f^{-1/2}$ . A maximum  $D^*$  of  $4.23 \times 10^7$  cm·Hz<sup>1/2</sup>/W at 100 Hz has been obtained.

In summary, the high quality pyroelectric LiTaO<sub>3</sub> thin films have been fabricated on Pt(111)/SiO<sub>2</sub>/Si(100) substrates by a diol-based sol-gel technology, and the optical response of the LiTaO<sub>3</sub> thin film detector were also investigated. The corresponding results of dynamic response show that the obtained LiTaO<sub>3</sub> thin film exhibited excellent pyroelectric properties and, thus, was suitable for application as highly sensitive pyroelectric IR devices.

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